

CFW
TSMC-00-101C



April 30, 2004

To: Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572
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Subject:

Serial No. 10/812,734 03/30/04

Shau-Lin Shue et al.

METHOD FOR FORMING A SELF-PASSIVATED
COPPER INTERCONNECT STRUCTURE

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation
In An Application.

The following Patents and/or Publications are submitted to
comply with the duty of disclosure under CFR 1.97-1.99 and
37 CFR 1.56.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being
deposited with the United States Postal Service as first class
mail in an envelope addressed to: Commissioner for Patents,
P.O. Box 1450, Alexandria, VA 22313-1450 on May 4, 2004.

Stephen B. Ackerman, Reg.# 37761

Signature/Date

Steph B. Ackerman 5/4/04

U.S. Patent 5,913,147 to Dubin et al., "Method for Fabricating Copper-Aluminum Metallization," discloses a layer over a Cu alloy plug.

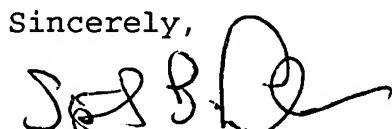
U.S. Patent 5,728,629 to Mizuno et al., "Process for Preventing Deposition on Inner Surfaces of CVD Reactor," discloses a passivation process.

U.S. Patent 5,714,418 to Bai et al., "Diffusion Barrier for Electrical Interconnects in an Integrated Circuit," discloses a Cu interconnect.

U.S. Patent 5,391,517 to Gelatos et al., "Process for Forming Copper Interconnect Structure," discloses a Cu interconnect.

U.S. Patent 6,046,108 to Liu et al., "Method for Selective Growth of Cu₃Ge or Cu₅Si for Passivation of Damascene Copper Structures and Device Manufactured Thereby," discloses a layer over a Cu plug.

Sincerely,



Stephen B. Ackerman,
Reg. No. 37761

win a lot!

INFORMATION DISCLOSURE CITATION
IN AN APPLICATION.

(Use several sheets if necessary) MAY 06 2004

MAY 06 2004

Doctor Name (Optional)

TSMC-00-101C 10 812,734

Lyonne Number

Shau-Lin Shue et al.

Filing Date

Filing Date 03/30/04 Group A1 Unit

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~~U. S.~~ PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

OTHER DOCUMENTS (Including Author, Title, Date, Portion/Pages, Etc.)

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.